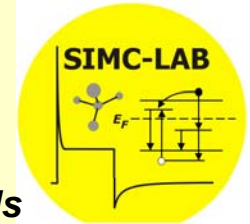


Institute of Electronic Materials Technology

*Joint Laboratory for Characterisation
of Defect Centres in Semi-Insulating Materials*



Annealing induced evolution of defect centres in MCz silicon irradiated with a neutron fluence of $1 \times 10^{16} \text{ cm}^{-2}$

Paweł Kamiński, Roman Kozłowski, and Barbara Surma

*Institute of Electronic Materials Technology,
133 Wólczyńska Str. 01-919 Warszawa, Poland*

Outline

- Samples – annealing conditions
- HRPITS images of spectral fringes for radiation defects in neutron-irradiated MCz silicon – effect of annealing on defect structure of material irradiated with a fluence of $1 \times 10^{16} \text{ cm}^{-2}$
- Photoluminescence results – defect model for the W-line
- Conclusions

Samples

Starting material:

Okmetic MCz <100> silicon wafers, *n*-type, 1 kΩcm, 300 μm thick

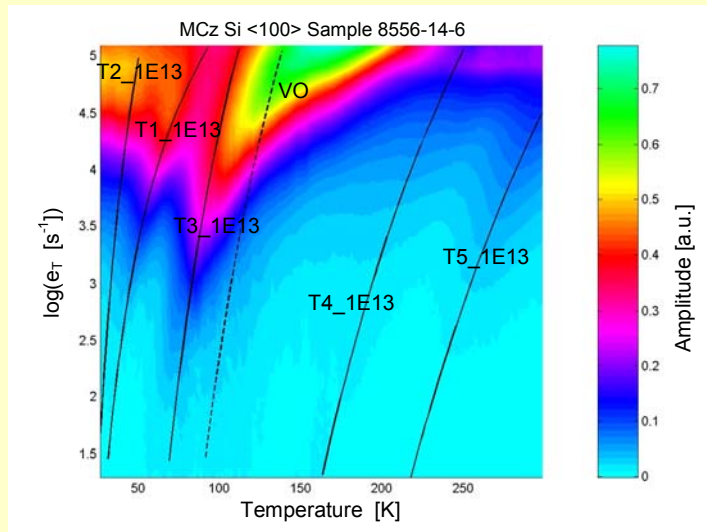
$$[O] = 5.5 \times 10^{17} \text{ cm}^{-3}$$

$$[C] = 2.5 \times 10^{15} \text{ cm}^{-3}$$

Neutron irradiation:

TRIGA reactor in Ljubljana, 1-MeV, fluences: 1×10^{12} , 1×10^{13} , 1×10^{14} , 3×10^{14} , 1×10^{15} , 3×10^{15} , **1×10^{16}** , and $3 \times 10^{16} \text{ cm}^{-2}$

Effect of neutron fluence on defect structure of as-irradiated material

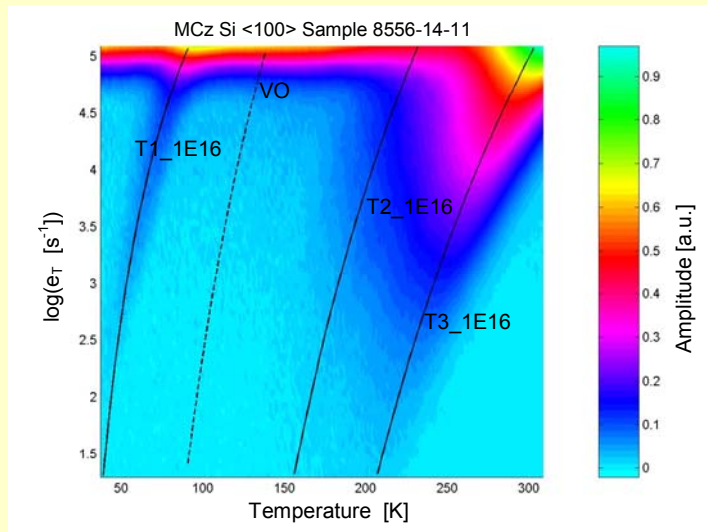


$\rho = \sim 4.0 \times 10^4 \Omega \text{cm}$

1-MeV neutron fluence $1 \times 10^{13} \text{ cm}^{-2}$

Trap label	E_a [meV]	A [$\text{s}^{-1}\text{K}^{-2}$]	Tentative Identification
T1_1E13	25 ± 2	$(2-5) \times 10^2$	shallow donor
T2_1E13	30 ± 2	$(3-6) \times 10^4$	shallow donor
T3_1E13	115 ± 5	$(8-20) \times 10^5$	$\text{C}_i\text{C}_s(\text{B})^{-/0}$ or self-interstitials related
T4_1E13	315 ± 10	$(2-4) \times 10^6$	$\text{V}_2^{2-/-} + \text{C}_i\text{O}_i^{+/0}$
T5_1E13	470 ± 20	$(1-5) \times 10^7$	$\text{V}_2^{-/0} + \text{V}_2\text{O}^{-/0}$

VO: $E_a = 0.17 \text{ eV}$; $A = 9.6 \times 10^6 \text{ s}^{-1}\text{K}^{-2}$



$\rho = \sim 5.0 \times 10^5 \Omega \text{cm}$, decrease in charge carriers lifetime at 250 K by two orders of magnitude

1-MeV neutron fluence $1 \times 10^{16} \text{ cm}^{-2}$

Trap label	E_a [meV]	A [$\text{s}^{-1}\text{K}^{-2}$]	Identification
T1_1E16	41 ± 3	$(1-3) \times 10^3$	self-interstitials, mono-interstitials (<i>I</i>)
T2_1E16	325 ± 10	$(1-5) \times 10^7$	$\text{V}_2^{2-/-} + \text{C}_i\text{O}_i^{+/0}$
T3_1E16	455 ± 15	$(1-5) \times 10^7$	$\text{V}_2^{-/0} + \text{V}_2\text{O}^{-/0} + \text{X}$ (vacancy aggregates)

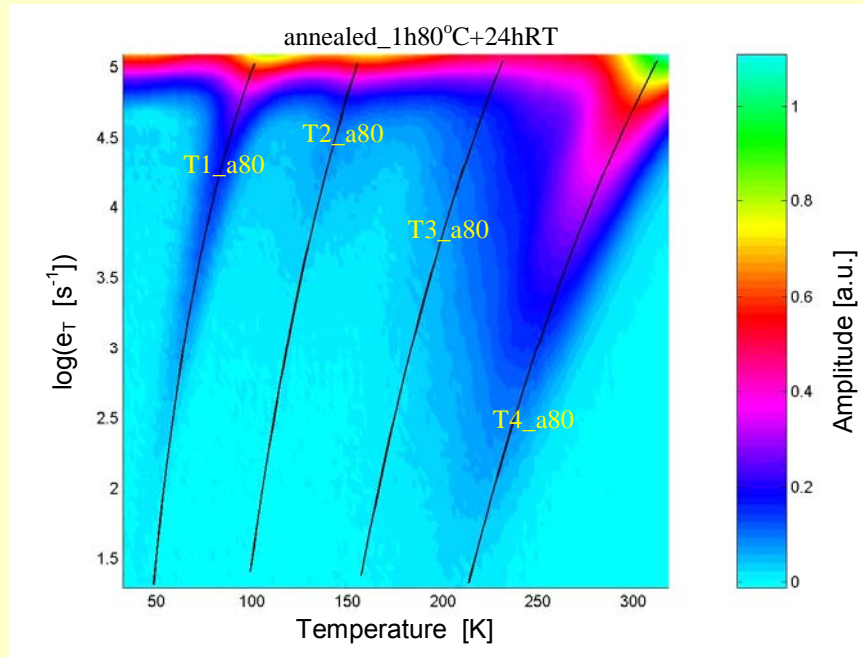
Annealing stages

HT1: 1h, 80 °C + 24 h, RT

HT2: (1h, 80 °C + 24 h, RT) + 1h, 160 °C + 24 h, RT

HT3: (1h, 80 °C + 24 h, RT + 1h, 160 °C + 24 h, RT) + 1h, 240 °C + 24 h, RT

HRPITS image after annealing HT1 (1h, 80 °C + 24 h, RT)

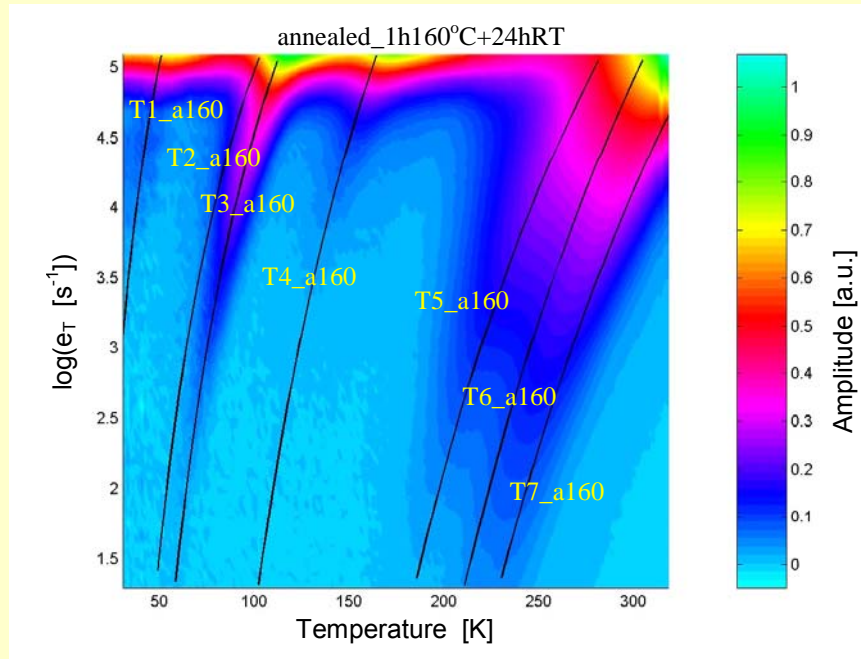


Laser: 650 nm, 5mW;
 $U_A = 20$ V;
 Gain: 1×10^7 V/A;
 Line width [samples]: 50000;
 Time Resolution [μ s]: 5
 Period [ms]: 263; Average: 500;
 Illumination pulse width: 50 ms

$\rho = \sim 6.0 \times 10^5 \Omega \text{cm}$
 τ/τ (as-irr.) = 0.66
 $E_{\text{TDDC}} = 428 \text{ meV}$

Trap label	E_a [meV]	A [$\text{s}^{-1}\text{K}^{-2}$]	e_1 [s^{-1}]	Amp_{e1} [a.u.]	e_2 [s^{-1}]	Amp_{e2} [a.u.]	Tentative identification
T1_a80	55 ± 5	$(5-7) \times 10^3$	1×10^3	0.042	3.2×10^4	0.188	di-interstitials (I_2)
T2_a80	175 ± 5	$(2-3) \times 10^6$	1×10^3	0.01	3.2×10^4	0.1	$\text{VO}^{-/0} + \text{V}_2\text{O}^{2-/-}$
T3_a80	325 ± 10	$(1-5) \times 10^7$	1×10^3	0.03	3.2×10^4	0.13	$\text{V}_2^{2-/-} + \text{C}_i\text{O}_i^{+/0}$
T4_a80	455 ± 15	$(1-5) \times 10^7$	1×10^3	0.14	3.2×10^4	0.43	$\text{V}_2^{-/0} + \text{V}_2\text{O}^{-/0} +$ X (vacancy aggregates)

HRPITS image after annealing HT2 (1h, 80 °C + 24 h, RT) + (1h, 160 °C + 24 h, RT)

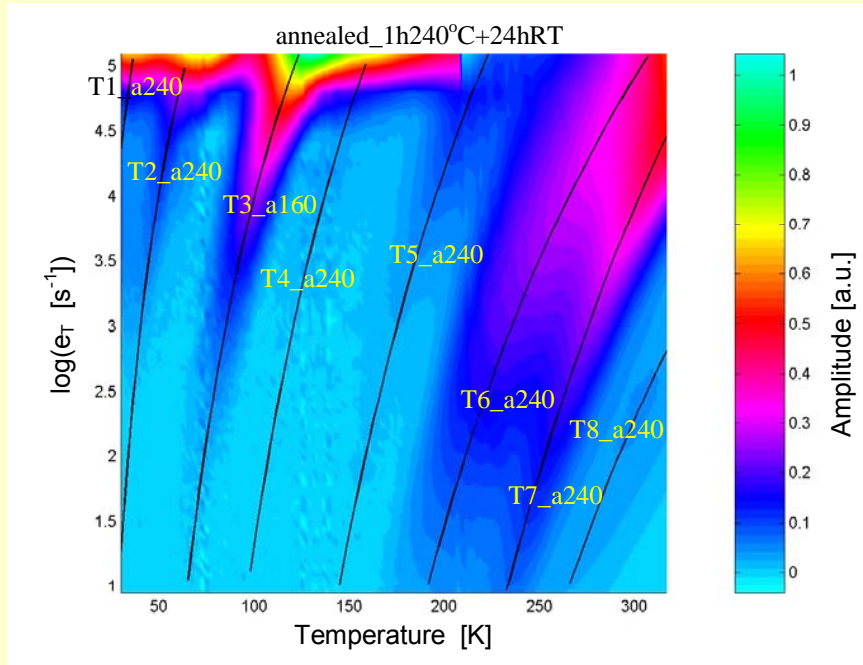


Laser: 650 nm, 5mW;
 $U_A = 20$ V;
 Gain: 1×10^7 V/A;
 Line width [samples]: 50000;
 Time Resolution [μ s]: 5
 Period [ms]: 263; Average: 500;
 Illumination pulse width: 50 ms

$\rho = \sim 2.5 \times 10^5 \Omega \text{cm}$
 τ/τ (as-irr.) = 2.41
 $E_{\text{TDDC}} = 400 \text{ meV}$

Trap label	E_a [meV]	A [$\text{s}^{-1}\text{K}^{-2}$]	e_1 [s^{-1}]	Amp_{e1} [a.u.]	e_2 [s^{-1}]	Amp_{e2} [a.u.]	Tentative identification
T1_a160	25 ± 2	$(1-2) \times 10^4$	3.2×10^3	0.014	3.2×10^4	0.09	shallow donor
T2_a160	55 ± 5	$(5-7) \times 10^3$	1×10^3	0.027	3.2×10^4	0.16	di-interstitials (I_2)
T3_a160	75 ± 5	$(2-4) \times 10^4$	1×10^3	0.08	3.2×10^4	0.35	tri-interstitials (I_3)
T4_a160	180 ± 5	$(9-20) \times 10^5$	1×10^3	0.01	3.2×10^4	0.11	$\text{VO}^{-/0} + \text{V}_2\text{O}^{2-/-}$
T5_a160	360 ± 10	$(3-5) \times 10^6$	1×10^3	0.12	3.2×10^4	0.3	$\text{C}_i\text{O}_i^{+/0}$
T6_a160	465 ± 15	$(2-5) \times 10^7$	1×10^3	0.15	3.2×10^4	0.4	$\text{V}_2^{-/0} + \text{V}_2\text{O}^{-/0}$
T7_a160	500 ± 15	$(5-7) \times 10^7$	1×10^3	0.14	3.2×10^4	0.43	EX3, TH6

HRPITS image after annealing HT3 (1h, 80 °C + 24 h, RT) + (1h, 160 °C + 24 h, RT) + (1h, 240 °C + 24 h, RT)

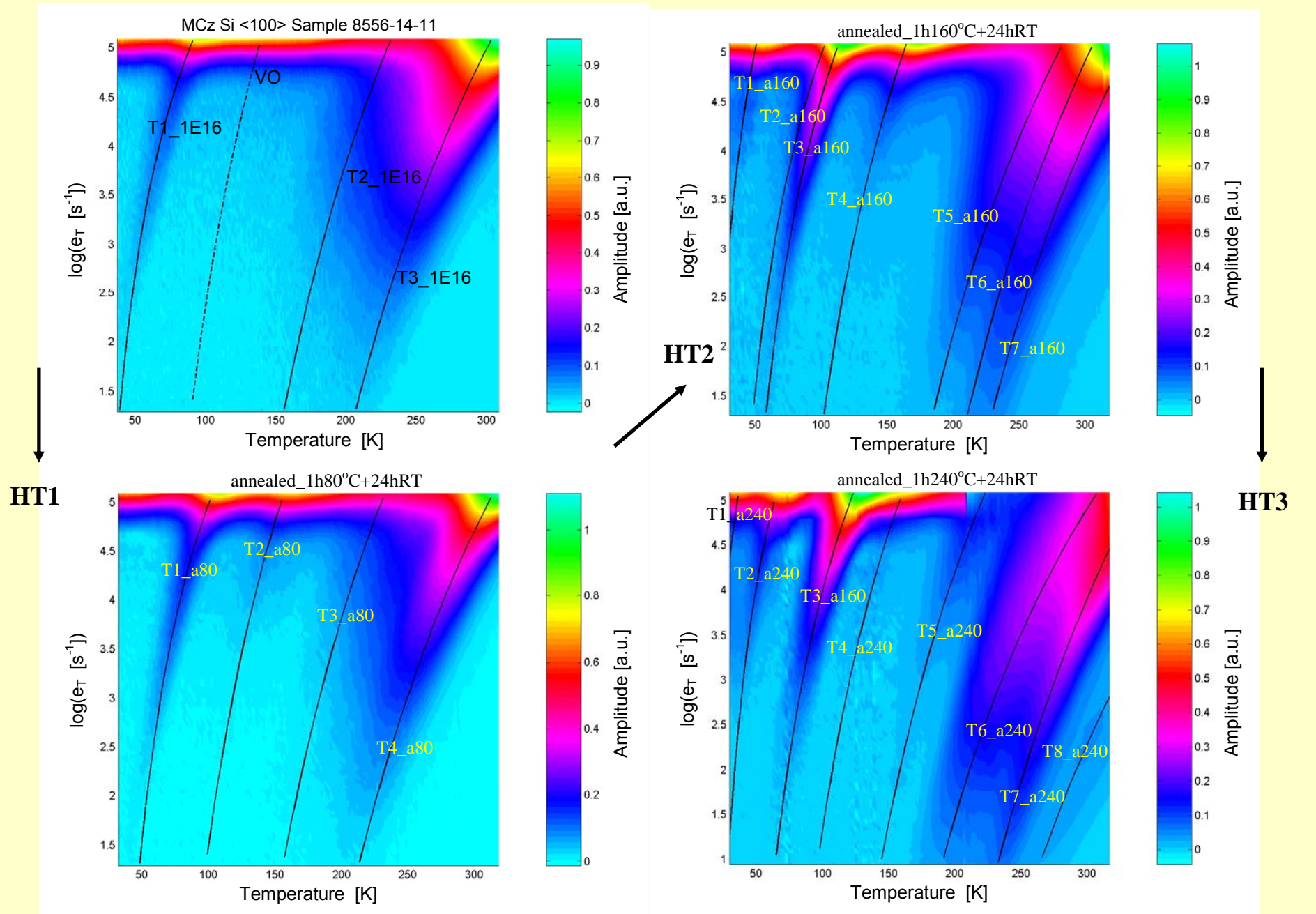


Laser: 650 nm, 5mW;
 $U_A = 20$ V;
 Gain: 1×10^7 V/A (20-210 K) and
 1×10^6 V/A (210-320 K) ;
 Line width [samples]: 50000;
 Time Resolution [μ s]: 10
 Period [ms]: 526; Average: 500;
 Illumination pulse width: 50 ms

$\rho = \sim 5.0 \times 10^4 \Omega \text{cm}$
 τ/τ (as-irr.) = 7.94
 $E_{\text{TDDC}} = 394 \text{ meV}$

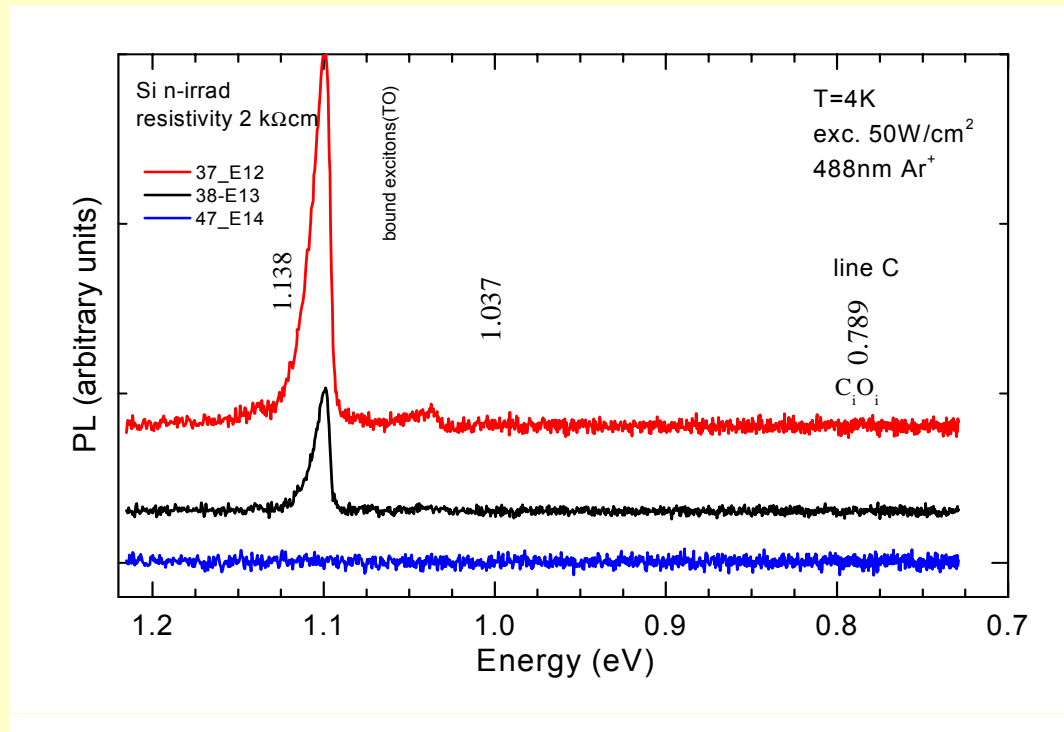
Trap label	E_a [meV]	A [$\text{s}^{-1}\text{K}^{-2}$]	e_1 [s^{-1}]	Amp_{e1} [a.u.]	e_2 [s^{-1}]	Amp_{e2} [a.u.]	Tentative identification
T1_a240	18±2	(2-4) $\times 10^4$	-	-	3.2×10^4	0.06	shallow donor
T2_a240	35±5	(1-2) $\times 10^4$	1×10^3	0.018	3.2×10^4	0.15	shallow donor
T3_a240	95±5	(5-8) $\times 10^4$	1×10^3	0.09	3.2×10^4	0.42	$I_2 + I_3$ + tetra-interstitials (I_4)
T4_a240	177±5	(1-3) $\times 10^6$	1×10^3	0.01	3.2×10^4	0.047	VO^{-0}
T5_a240	300±10	(1-3) $\times 10^7$	1×10^3	0.027	3.2×10^4	0.11	$\text{C}_i, \text{C}_i\text{-I}?$
T6_a240	370±15	(1-3) $\times 10^6$	1×10^3	0.21	3.2×10^4	0.31	$\text{C}_i\text{O}_i^{0/+}$
T7_a240	540±15	(2-3) $\times 10^6$	1×10^3	0.25	3.2×10^4	0.49	I level, $E_c - 0.545 \text{ eV}$, V_3
T8_a240	560±15	(2-3) $\times 10^8$	1×10^2	0.036	2.5×10^2	0.042	$E_v + 0.58 \text{ eV}$ (?)

Summary of HRPITS images after each step of annealing



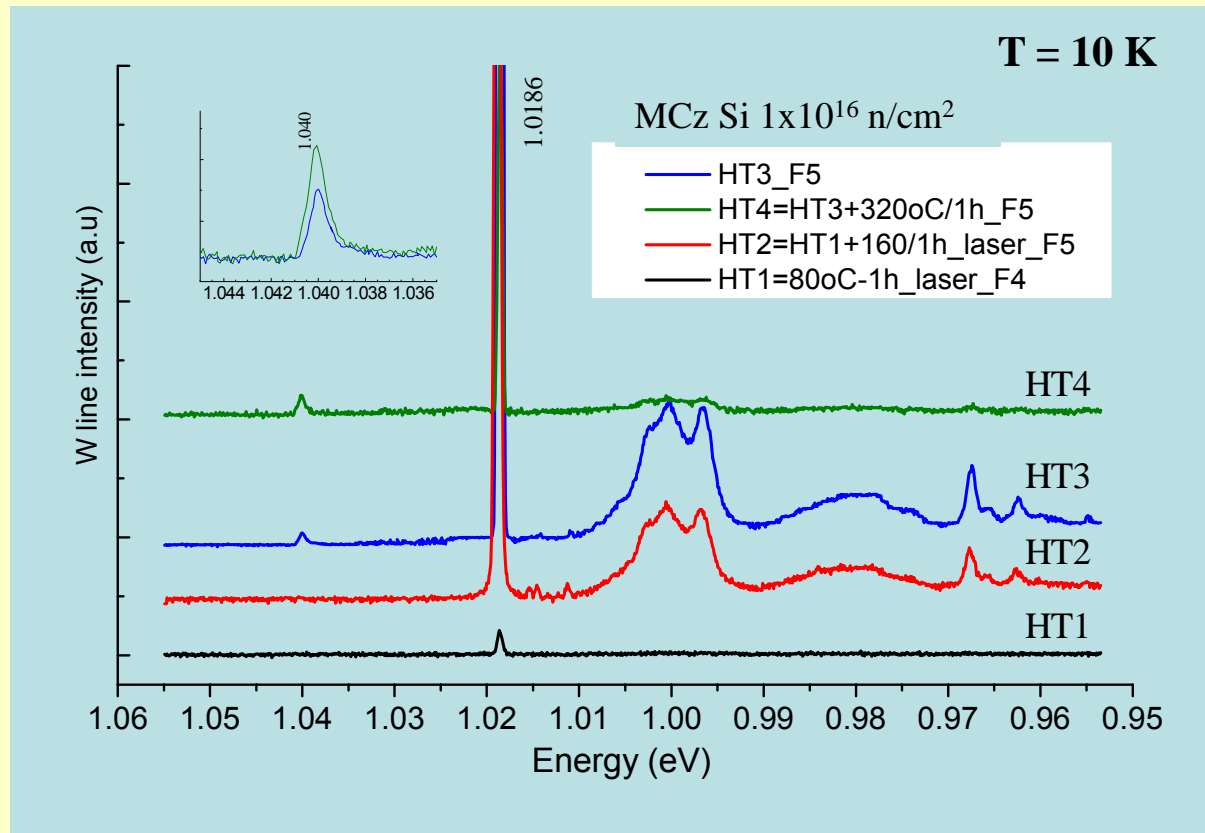
Photoluminescence results

The PL measurements were done using Ar⁺ laser operated at 488 nm focused to a spot of about 400 micrometers. The luminescence at 4.0-4.3 K was detected using lock-in technique and Hamamatsu photomultiplier type R5509-72 with InGaAsP cathode. The spatial resolution was 1.5 nm for 1 μm. The samples were placed on a cool finger and cooled down by using the closed-cycle cooling system.



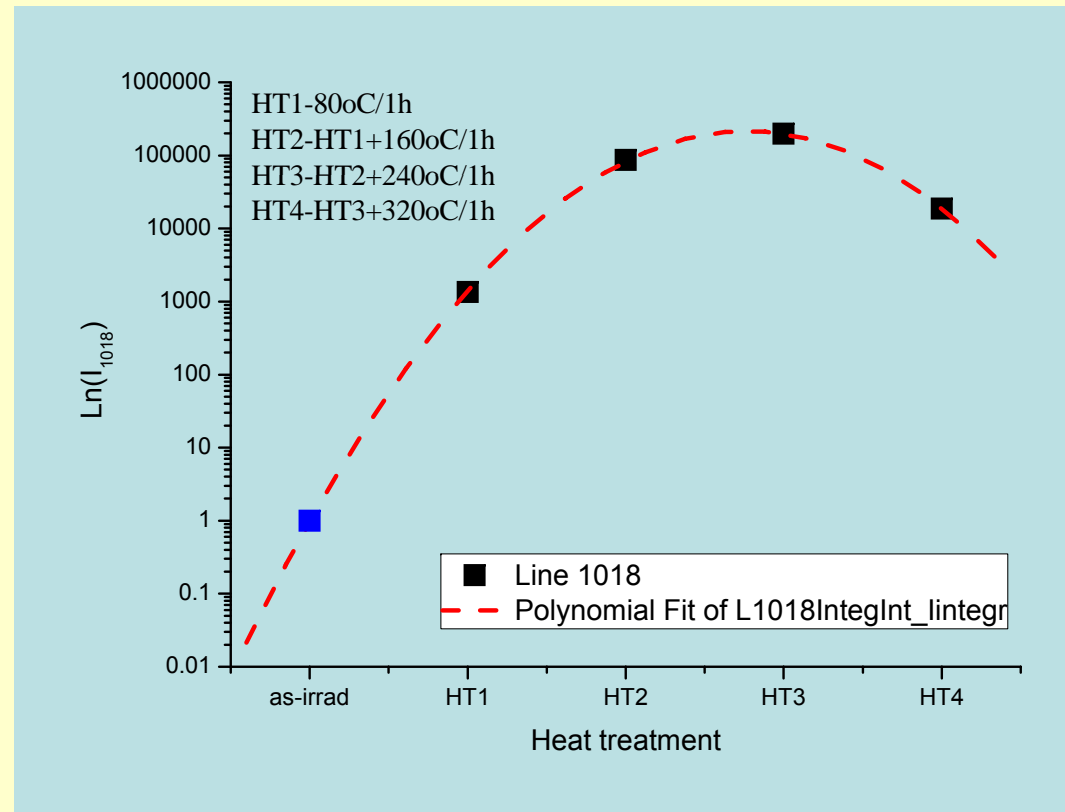
Comparison of photoluminescence spectra for MCz Si samples irradiated with neutron fluences of 1×10^{12} , 1×10^{13} and 1×10^{14} cm⁻². The decrease in the radiative recombination efficiency with increasing the fluence is seen.

Photoluminescence results



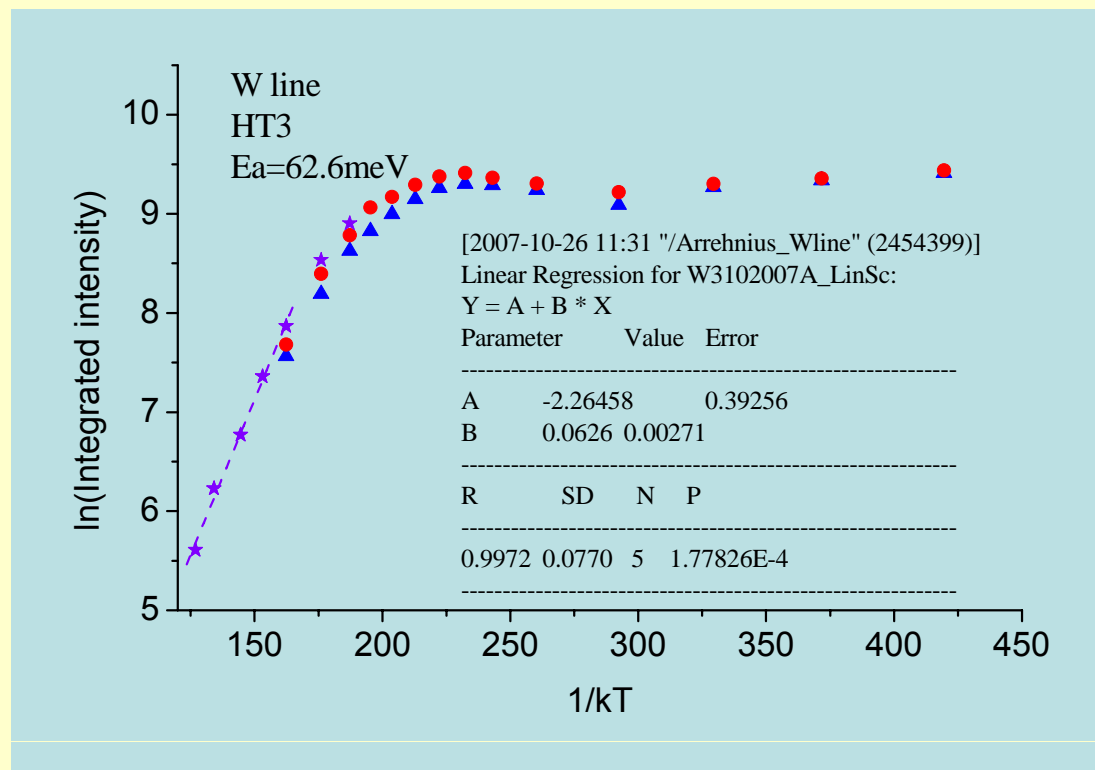
PL spectra taken after each annealing stage for a sample of 1k Ω cm MCz-Si exposed to 1-MeV neutron irradiation with a fluence of 1×10^{16} cm⁻². A strong increase in the intensity of the *W* line (at 1018 meV) with the rise of the annealing temperature is seen.

Photoluminescence results



Intensity of the luminescence from the W line (at 1018 meV), measured at 10 K, as a function annealing temperature. The W line is increasing due to restructuring within small clusters.

Photoluminescence results – Defect model for the W line



Main facts

- not affected by the impurities
- occurs after annealing at $\sim 100\text{C}$
- interstitial related
- detailed structure and defect interactions still discussed

Minoru Nakamura and Siro Nagai
PHYSICAL REVIEW B **66**, 155204
(2002)

Gordon Davis *et al.*
PHYSICAL REVIEW B **73**, 165202
(2006)

Temperature dependence of the *W* line (at 1018 meV) intensity. The straight line due to the thermal emission of charge carriers is obtained in the temperature range 50 – 100 K. In the same range the HRPITS fringes assigned to self-interstitials are observed. The activation energy of the *W* center 62.6 meV is close to the value of 55 meV determined for defect centers T1_a80 and T2_a160 attributed to di-interstitials (I_2).

Conclusions

- High-resolution photoinduced transient spectroscopy (HRPITS) with implementation of the imaging procedure and photoluminescence (PL) measurements have been used to studying the annealing-induced evolution of defect centers in 1-kΩcm MCz-Si exposed to irradiation of 1-MeV neutrons with a fluence of $1 \times 10^{16} \text{ cm}^{-2}$.
- After the first stage of heat treatment at 80 °C for 1h, the activation energy of shallow defects increased from 41 to 55 meV. This change has been proposed to be due to the formation of di-interstitials (I_2). The annealing also resulted in narrowing the broad HRPITS band related to vacancy clusters introducing nearly midgap levels and appearing the VO center.
- As a result of the second stage of isochronal annealing at 160 °C, the 25-meV shallow donor arose and besides the 55-meV level of di-interstitials, the 75-meV level assigned to tri-interstitials (I_3) occurred. On the other hand, the 360-meV level corresponding to C_iO_i complex and the 500-meV level of an unknown defect were well resolved.
- After the third stage of annealing at 240 °C, the 18-meV and 35-meV shallow donors and the 95-meV level assigned to tetra-interstitials (I_4) were detected. On the other hand, the defect centers related to divacancies disappeared and two midgap centers with the activation energies of 540 meV and 560 meV were revealed.
- The activation energy of the W line in the PL spectra was found to be ~ 63 meV and is close to that of 55 meV determined from HRPITS measurements for the defect center attributed to di-interstitials. This result indicates that the same defect is observed by the both methods and supports the defect model assigning the W center to di-interstitials.

Acknowledgement

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